

# Han Haitjema

## List of Publications by Year in descending order

Source: <https://exaly.com/author-pdf/1416028/publications.pdf>

Version: 2024-02-01

85  
papers

3,219  
citations

236833

25  
h-index

155592

55  
g-index

85  
all docs

85  
docs citations

85  
times ranked

1690  
citing authors

#	ARTICLE	IF	CITATIONS
1	Depolarization of surface scattering in polarized laser scattering detection for machined silicon wafers. Precision Engineering, 2022, 73, 203-213.	1.8	6
2	3D total variation denoising in X-CT imaging applied to pore extraction in additively manufactured parts. Measurement Science and Technology, 2022, 33, 045602.	1.4	4
3	Stylus tip radius and wear estimation using the Rsk or the Rp and Rv parameter of a sine wave (Type C1) standard. Surface Topography: Metrology and Properties, 2022, 10, 015025.	0.9	0
4	On-machine chromatic confocal measurement for micro-EDM drilling and milling. Precision Engineering, 2022, 76, 110-123.	1.8	15
5	International comparison of flatness deviation in areal surface topography measurements. CIRP Annals - Manufacturing Technology, 2022, 71, 453-456.	1.7	3
6	Surface profile and topography filtering by Legendre polynomials. Surface Topography: Metrology and Properties, 2021, 9, 015017.	0.9	5
7	Uncertainty evaluation and reduction in three-probe roundness profile measurement based on the system transfer function. Precision Engineering, 2021, 68, 139-157.	1.8	4
8	International comparison of noise in areal surface topography measurements. Surface Topography: Metrology and Properties, 2021, 9, 025015.	0.9	8
9	Texture of inclined up-facing surfaces in laser powder bed fusion of metals. Additive Manufacturing, 2021, 42, 101970.	1.7	7
10	Metrology: A New Open Access Journal with a Broad Scope and an Exciting Mission. Metrology, 2021, 1, 74-75.	0.9	0
11	Hybrid dual laser processing for improved quality of inclined up-facing surfaces in laser powder bed fusion of metals. Journal of Materials Processing Technology, 2021, 298, 117263.	3.1	16
12	Metrological characteristics for the calibration of surface topography measuring instruments: a review. Measurement Science and Technology, 2021, 32, 032001.	1.4	39
13	Digital Twin of an Optical Measurement System. Sensors, 2021, 21, 6638.	2.1	15
14	Description and validation of a circular padding method for linear roughness measurements of short data lengths. MethodsX, 2020, 7, 101122.	0.7	1
15	Two-dimensional detection of subsurface damage in silicon wafers with polarized laser scattering. Journal of Materials Processing Technology, 2020, 284, 116746.	3.1	18
16	The Calibration of Displacement Sensors. Sensors, 2020, 20, 584.	2.1	14
17	Straightness, flatness and cylindricity characterization using discrete Legendre polynomials. CIRP Annals - Manufacturing Technology, 2020, 69, 457-460.	1.7	8
18	Calibration of Displacement Laser Interferometer Systems for Industrial Metrology. Sensors, 2019, 19, 4100.	2.1	22

#	ARTICLE	IF	CITATIONS
19	On-machine and in-process surface metrology for precision manufacturing. CIRP Annals - Manufacturing Technology, 2019, 68, 843-866.	1.7	259
20	Advanced Optical Incremental Sensors. , 2018, , 245-290.		3
21	Bio-inspired textures for functional applications. CIRP Annals - Manufacturing Technology, 2018, 67, 627-650.	1.7	88
22	Surface Texture Metrological Characteristics. , 2018, , 1-5.		2
23	An international comparison of surface texture parameters quantification on polymer artefacts using optical instruments. CIRP Annals - Manufacturing Technology, 2016, 65, 529-532.	1.7	27
24	Flatness. , 2016, , 1-6.		1
25	Measurement Uncertainty. , 2016, , 1-5.		0
26	Revisiting the multi-step method: Enhanced error separation and reduced amount of measurements. CIRP Annals - Manufacturing Technology, 2015, 64, 491-494.	1.7	23
27	Uncertainty in measurement of surface topography. Surface Topography: Metrology and Properties, 2015, 3, 035004.	0.9	49
28	Measurement technologies for precision positioning. CIRP Annals - Manufacturing Technology, 2015, 64, 773-796.	1.7	397
29	Calibration and verification of areal surface texture measuring instruments. CIRP Annals - Manufacturing Technology, 2015, 64, 797-813.	1.7	96
30	Length Traceability Using Interferometry. , 2014, , 63-93.		0
31	Role of surfaces and interfaces in solar cell manufacturing. CIRP Annals - Manufacturing Technology, 2014, 63, 797-819.	1.7	28
32	Roughness. , 2014, , 1080-1082.		0
33	Reflectivity. , 2014, , 1042-1044.		0
34	Flatness. , 2014, , 1-5.		1
35	Measurement Uncertainty. , 2014, , 852-857.		1
36	Ellipsometry. , 2014, , 453-458.		0

#	ARTICLE	IF	CITATIONS
37	Uncertainty estimation of 2.5-D roughness parameters obtained by mechanical probing. International Journal of Precision Technology, 2013, 3, 403.	0.2	6
38	Task specific uncertainty estimation in dimensional metrology. International Journal of Precision Technology, 2011, 2, 226.	0.2	10
39	Bandwidth characteristics and comparisons of surface texture measuring instruments. Measurement Science and Technology, 2010, 21, 079801.	1.4	19
40	Bandwidth characteristics and comparisons of surface texture measuring instruments. Measurement Science and Technology, 2010, 21, 032001.	1.4	82
41	Geometric error measurement and compensation of machines—An update. CIRP Annals - Manufacturing Technology, 2008, 57, 660-675.	1.7	757
42	Achieving traceability and sub-nanometer uncertainty using interferometric techniques. Measurement Science and Technology, 2008, 19, 084002.	1.4	21
43	Dimensional Micro and Nano Metrology. CIRP Annals - Manufacturing Technology, 2006, 55, 721-743.	1.7	273
44	Development of a double sided stitching interferometer for wafer characterization. CIRP Annals - Manufacturing Technology, 2006, 55, 555-558.	1.7	16
45	The detection of cyclic nonlinearities in a ZMI2000 heterodyne interferometer. , 2005, 5879, 205.		1
46	Accurate roughness measurements by laser interferometer calibration, VFM-uncertainty calculations and noise reduction. , 2005, 5879, 170.		0
47	Accurate roughness measurements by dynamic calibration, VFM-uncertainty calculations and a special calibration specimen. Journal of Physics: Conference Series, 2005, 13, 232-235.	0.3	2
48	Noise bias removal in profile measurements. Measurement: Journal of the International Measurement Confederation, 2005, 38, 21-29.	2.5	40
49	Validation of a single fibre-fed heterodyne laser interferometer with nanometre uncertainty. Precision Engineering, 2005, 29, 229-236.	1.8	10
50	Fiber characterization for application in heterodyne laser interferometry, part II: modeling and analysis. Optical Engineering, 2005, 44, 025003.	0.5	2
51	Fiber characterization for application in heterodyne laser interferometry with nanometer uncertainty, part I: polarization state measurements. Optical Engineering, 2005, 44, 025002.	0.5	5
52	Scanning wafer thickness and flatness interferometer. , 2004, 5252, 334.		17
53	NOISE CORRECTION FOR SURFACE MEASUREMENTS. , 2004, , .		2
54	Laser Polarization State Measurement in Heterodyne Interferometry. CIRP Annals - Manufacturing Technology, 2003, 52, 439-442.	1.7	8

#	ARTICLE	IF	CITATIONS
55	Improving a commercially available heterodyne laser interferometer to sub-nm uncertainty. , 2003, , .		13
56	Method for approximate noise elimination in form and roughness measurements. , 2003, , .		2
57	A novel technique for calibration of polygon angles with non-integer subdivision of indexing table. Precision Engineering, 2002, 26, 412-424.	1.8	22
58	Modeling and verifying non-linearities in heterodyne displacement interferometry. Precision Engineering, 2002, 26, 448-455.	1.8	113
59	CALCULATION OF MEASUREMENT UNCERTAINTY FOR MULTI-DIMENSIONAL MACHINES, USING THE METHOD OF SURROGATE DATA. , 2001, , .		6
60	Uncertainty estimation by the concept of virtual instruments. , 2001, , .		15
61	Calibration of nanosensors with direct traceability to the meter. , 2001, , .		1
62	Novel design of a one-dimensional measurement probe. , 2001, , .		3
63	Development of a Silicon-based Nanoprobe System for 3-D Measurements. CIRP Annals - Manufacturing Technology, 2001, 50, 365-368.	1.7	75
64	A silicon-etched probe for 3-D coordinate measurements with an uncertainty below 0.1 $\hat{\mu}$ m. IEEE Transactions on Instrumentation and Measurement, 2001, 50, 1519-1523.	2.4	27
65	Virtual CMM using Monte Carlo methods based on frequency content of the error signal. , 2001, , .		20
66	Calibration of displacement sensors up to 300 $\hat{\mu}$ m with nanometre accuracy and direct traceability to a primary standard of length. Metrologia, 2000, 37, 25-33.	0.6	46
67	International comparisons of He-Ne lasers stabilized with $^{127}I_2$ at $\hat{\lambda} = 633$ nm (July 1993 to September 1995). Part IV: Comparison of Western European lasers at $\hat{\lambda} = 633$ nm. Metrologia, 1999, 36, 199-206.	0.6	21
68	Deformation and wear of pyramidal, silicon-nitride AFM tips scanning micrometre-size features in contact mode. Measurement: Journal of the International Measurement Confederation, 1999, 25, 203-211.	2.5	61
69	Uncertainty analysis of roughness standard calibration using stylus instruments. Precision Engineering, 1998, 22, 110-119.	1.8	34
70	Design and calibration of a parallel-moving displacement generator for nano-metrology. Measurement Science and Technology, 1998, 9, 1098-1104.	1.4	32
71	<title>Long gauge block measurements based on a Twyman-Green interferometer and three stabilized lasers</title>. , 1998, 3477, 25.		9
72	<title>Ball diameter measuring instrument in a gauge block interferometer</title>. , 1998, 3477, 101.		3

#	ARTICLE	IF	CITATIONS
73	International comparison of depth-setting standards. Metrologia, 1997, 34, 161-167.	0.6	18
74	Dynamic probe calibration up to 10 kHz using laser interferometry. Measurement: Journal of the International Measurement Confederation, 1997, 21, 107-111.	2.5	6
75	Dynamic probe calibration in the $\hat{1}4$ m region with nanometric accuracy. Precision Engineering, 1996, 19, 98-104.	1.8	37
76	International comparison of roundness profiles with nanometric accuracy. Metrologia, 1996, 33, 67-73.	0.6	37
77	Physical properties of pyrolytically sprayed tin-doped indium oxide coatings. Thin Solid Films, 1991, 205, 93-100.	0.8	33
78	Relations between the optical, electrical, and structural properties of fluorine-doped tin dioxide coatings. , 1990, , .		2
79	Electrical properties of sprayed tin oxide layers. Thin Solid Films, 1989, 177, 17-33.	0.8	31
80	The optical, electrical and structural properties of fluorine-doped, pyrolytically sprayed tindioxide coatings. Solar Energy Materials and Solar Cells, 1989, 18, 283-297.	0.4	57
81	Analysis of tin dioxide coatings by multiple angle of incidence ellipsometry. Thin Solid Films, 1989, 169, 1-16.	0.8	22
82	The physical properties of fluorine-doped tin dioxide films and the influence of ageing and impurity effects. Solar Energy Materials and Solar Cells, 1987, 16, 79-90.	0.4	26
83	Investigations On Fluorine-Doped Tin Dioxide Films. Proceedings of SPIE, 1986, 0653, 137.	0.8	0
84	The Utrecht accelerator facility for precision dating with radionuclides. Nuclear Instruments & Methods in Physics Research B, 1984, 5, 150-154.	0.6	8
85	Sphericity Measurement Using Stitching Interferometry. Key Engineering Materials, 0, 523-524, 883-888.	0.4	8